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Amendment AF Transmittal

AF/6AM-1763 \$

TOWNSEND and TOWNSEND and CREW LLP  
(650) 326-2400

Attorney Docket No. AM2119/T21300  
TTC Ref No. 16301M-021300US

In re application of: KARL LITTAU et al.

Application No.: 08/893,917

Filed: July 11, 1997

Group Art Unit: 1763

For: REMOTE PLASMA CLEANING SOURCE HAVING  
REDUCED REACTIVITY WITH A SUBSTRATE  
PROCESSING CHAMBER



Date: May 4, 2000

I hereby certify that this is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

Box AF  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Signed: Lynda Robisch

Box AF  
ASSISTANT COMMISSIONER FOR PATENTS  
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application. Also enclosed are two return receipt postcards. If any extension of time is needed, then this response should be considered a petition therefor.

The filing fee has been calculated as shown below:

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA
TOTAL	* 21	MINUS	** 21	= 0
INDEP.	* 4	MINUS	*** 3	= 1
[ ] FIRST PRESENTATION OF MULTIPLE DEP. CLAIM				

SMALL ENTITY

RATE	ADDIT. FEE
x \$9.00 =	
x \$39.00 =	
+ \$130.00 =	
TOTAL	

RECEIVED  
MAY 15 2000  
OTHER THAN  
SMALL ENTITY  
TO 100 MAIL ROOM

RATE	ADDIT. FEE
x \$18.00 =	\$0.00
x \$78.00 =	\$78.00
+ \$260.00 =	
TOTAL	\$78.00

Please charge Deposit Account No. 20-1430 as follows:

[ X ] Claims fee \$ \$78.00  
[ X ] Any additional fees associated with this paper or during the pendency of this application.

2 extra copies of this sheet are enclosed.

05/11/2000 HNHCHNEL 00000002 201430 08893917

01 FC:102 78.00 CH

TOWNSEND and TOWNSEND and CREW LLP

Chun-Pok Letung  
Chun-Pok Letung  
Reg. No. 41,405  
Attorneys for Applicant

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

AMENDMENT UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE -  
EXAMINING GROUP 1763

Box AF

Assistant Commissioner for Patents  
Washington, D.C. 20231

PATENT

Attorney Docket No.: AM2119/T21300  
TTC No.: 16301M-021300

On May 4, 2000

TOWNSEND and TOWNSEND and CREW LLP

By: Lynda Robisch

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#1301E  
5/16/00  
ML

In re application of:

Karl Littau et al.

Application No.: 08/893,917

Filed: July 11, 1997

For: REMOTE PLASMA CLEANING  
SOURCE HAVING REDUCED  
REACTIVITY WITH A  
SUBSTRATE PROCESSING  
CHAMBER

Examiner: Rudy Zervigon

AMENDMENT UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 1763

RECEIVED  
MAY 15 2000  
TO 1700 MAIL ROOM

**Box AF**

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Final Office Action mailed March 10, 2000, and for the purpose of putting the application in condition for allowance, please amend this application as follows. If the amendments are not deemed to put the application in condition for allowance, please enter the amendments to narrow the issues for appeal.

IN THE CLAIMS:

Please amend claims 1, 4, 8, and 16 as follows. Note that the remaining claims are unamended, but are reproduced below for the Examiner's convenience and reference.

1. (Amended) A method of removing residue from a substrate processing chamber, said method comprising the steps of: